

## Electronic Patent Application Fee Transmittal

<b>Application Number:</b>	10585229				
<b>Filing Date:</b>					
<b>Title of Invention:</b>	System and method for selective etching of silicon nitride during substrate processing				
<b>First Named Inventor/Applicant Name:</b>	Ismail Kashkoush				
<b>Filer:</b>	Brian L. Belles/Kathleen Fletcher				
<b>Attorney Docket Number:</b>	ARK002-108430.040-US				
Filed as Small Entity					
<b>U.S. National Stage under 35 USC 371 Filing Fees</b>					
<b>Description</b>		<b>Fee Code</b>	<b>Quantity</b>	<b>Amount</b>	<b>Sub-Total in USD(\$)</b>
<b>Basic Filing:</b>					
<b>Pages:</b>					
<b>Claims:</b>					
<b>Miscellaneous-Filing:</b>					
Late filing fee for oath or declaration	2051	1	65	65	
<b>Petition:</b>					
<b>Patent-Appeals-and-Interference:</b>					
<b>Post-Allowance-and-Post-Issuance:</b>					
<b>Extension-of-Time:</b>					

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
<b>Miscellaneous:</b>				
<b>Total in USD (\$)</b>				<b>65</b>